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PATENT

**IN THE UNITED STATES PATENT
AND TRADEMARK OFFICE**

Applicant: Young-Soo Kim)

Serial No.: 10/615,038)

Filed: July 8, 2003)

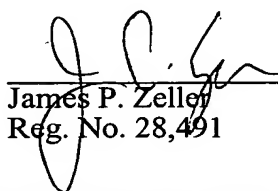
For: ATOMIC LAYER
DEPOSITION OF TITANIUM
NITRIDE USING BATCH TYPE
CHAMBER AND METHOD FOR
FABRICATING CAPACITOR BY
USING THE SAME)

Group Art Unit: 2891)

Examiner: Bradley Smith)

I hereby certify that this paper (or fee) is being
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March 6, 2006


James P. Zeller
Reg. No. 28,491

RESPONSE TO OFFICIAL ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is in response to the official action of March 1, 2006, forwarding an
interview summary summarizing the results of a telephonic interview conducted February 1,
2006, between the undersigned and Examiner Smith.

The interview summary states as follows:

“The examiner and the attorney for the application discussed
the initial allowance of claims 7 and subsequent cancellation of
claim 7. The examiner allowed claim 7 in error and
subsequently canceled claim 7 in an office action filed on
1/12/06. Furthermore, it was understood that claim 7 would
be filed in a divisional application.”

Applicant's undersigned attorney hereby confirms the accuracy and completeness of
the examiner's interview summary.

This application was allowed, and the issue fee was paid October 12, 2005. Prompt issuance of a patent is solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

March 6, 2006

By: 

James P. Zeller

Reg. No. 28,491

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